



Abstract

Apparatus and methods are disclosed for automated semiconductor device probing. The apparatus comprises: a probe assembly; a machine vision system; and a semiconductor support fixture. A method comprises: providing apparatus for automated semiconductor device probing; locating the semiconductor device positioned on the semiconductor support fixture with the machine vision system; guiding the movement of at least one of the probe assembly and the semiconductor support fixture so as to position a contact portion of the semiconductor device and the electrical probe in alignment with one another; and moving at least one of the probe assembly and the semiconductor support fixture toward the other of the at least one of the probe assembly and the semiconductor support fixture so as to position the electrical probe and the contact portion of the semiconductor device in electrical connection with one another.